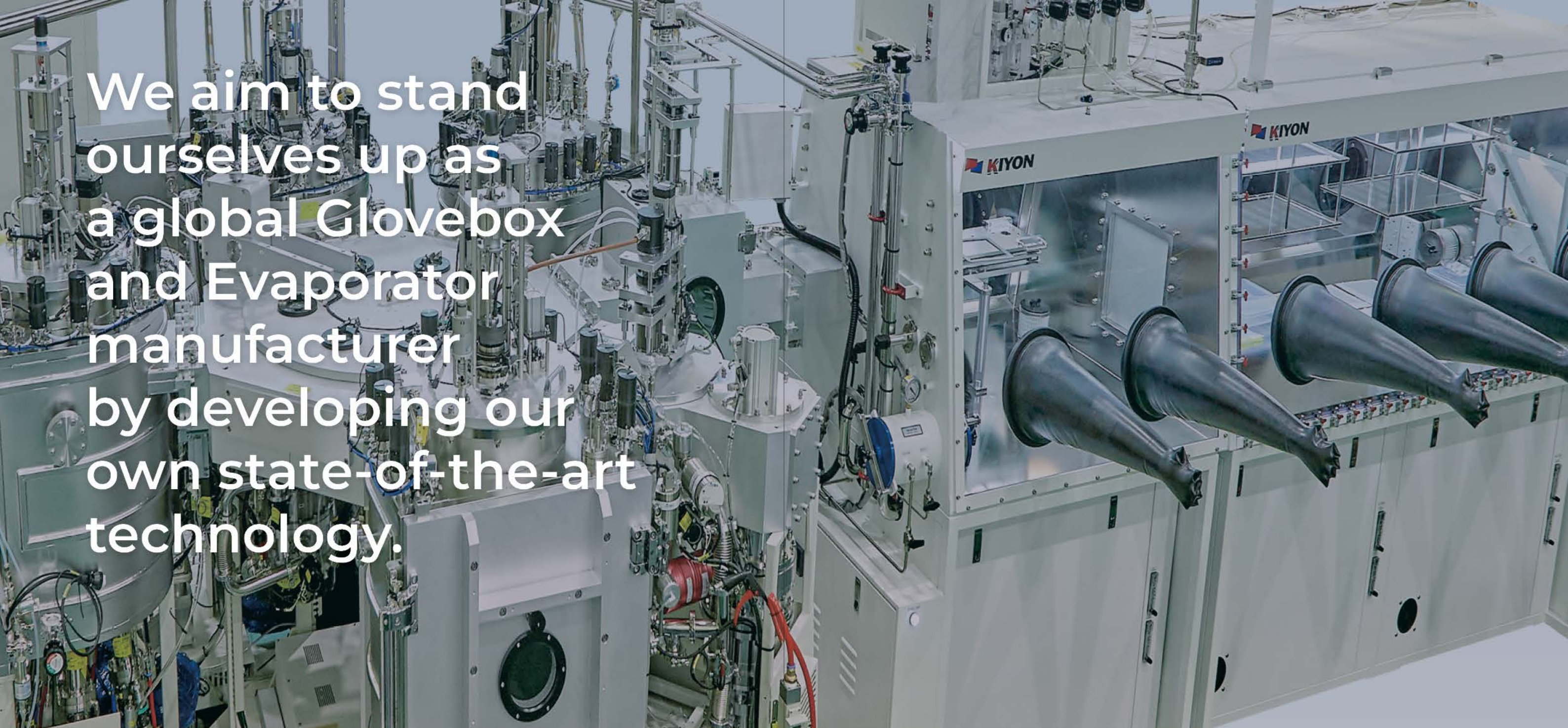


# Glovebox & Vacuum Deposition System

For All-Solid-State Batteries, Solar Cell, Semiconductor Components & Nuclear





We aim to stand ourselves up as a global Glovebox and Evaporator manufacturer by developing our own state-of-the-art technology.

- Thermal Evaporator
- Sputter
- E-Beam
- Tandem Deposition system
- Glovebox

You will discover our board range of capabilities built through almost 40 years of exceptional performance by delivering the most technologically advanced glovebox systems to our worldwide customers in the field of high-tech industries such as bio, chemistry, nuclear, solar cell, secondary cell, OLED glass, pharmaceuticals, medical R&D, and mass production automation.

Our product line-up has given many customers a perfectly controlled atmospheric environment and technical solutions. Our glovebox system is designed to provide 'a hermetically sealed and highly customized working space' under a perfectly controlled atmospheric environment, which is regarding 'less than 1 ppm in H<sub>2</sub>O and O<sub>2</sub> concentration levels', 'temperature control', 'consistent gas flow system' using an efficient laminar flow system, 'cooling systems' and so on.

As for the customers' higher requirements and stricter industrial standards, we, KOREA KIYON, have been trying to provide more reliable and industry-proven solutions to our existing and potential customers in the various application fields.

We would like to open a new era with our completely controlled atmosphere systems for the most efficient and effective R&D activities and productions of our customers. Thank you!!

## Thermal Evaporator / KESD-170



### Characteristics

- Standard Chamber Size: 450(W) x 450(D) x 550(H) mm
- Sample Size: 170 x 170 mm
- Vacuum Capacity:  $5.0 \times 10^{-7}$  torr
- Chamber Working Pressure: Less than  $5.0 \times 10^{-6}$  torr
- Film Thickness Uniformity:  $\pm 5\%$  within 156 x 156 mm Glass

### Design

- Sliding door allows easy and safe sample loading
- Isolated rear door for easy cleaning maintenance

### Configuration

- Auto Control by 10.5" Touch Panel  
(Auto Pumping, Auto Venting, Auto System Shut Down)
- Co-Deposition available
- Sample Rotation / Heating or Cooling(Optional)



## Sputter / KSSD-100



### Characteristics

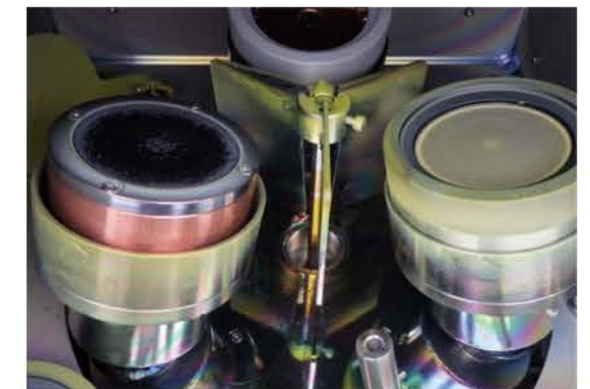
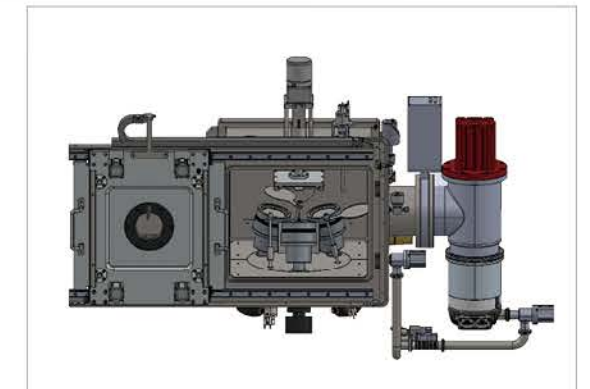
- Standard Chamber Size: 450(W) x 450(D) x 500(H) mm
- Sample Size: Max. 100 x 100 mm
- Vacuum Capacity:  $5.0 \times 10^{-7}$  torr
- Chamber Working Pressure: Less than  $5.0 \times 10^{-6}$  torr
- Cathode size: O.D 3" x 3 Sets
- Plasma Power Supply: RF & DC Power Supply
- Film Thickness Uniformity:  $\pm 5\%$  within 100 x 100mm Glass

### Design

- Sliding door allows easy and safe sample loading
- Isolated rear door for easy cleaning maintenance

### Configuration

- Auto Control by 10.5" Touch Panel  
(Auto Pumping, Auto Venting, Auto System Shut Down)



## E-Beam / KBSD-100



### Characteristics

- Standard Chamber Size: 450(W) x 450(D) x 500(H) mm
- Sample Size: Max. 100 x 100 mm
- E-Beam Power Capacity: 6 KW
- E-Beam Gun: 7cc x 6 Pockets
- Vacuum Capacity:  $5.0 \times 10^{-7}$  torr
- Chamber Working Pressure: Less than  $5.0 \times 10^{-6}$  torr
- Film Thickness Uniformity:  $\pm 5\%$  within 100 x 100 mm Glass



### Design

- Sliding door allows easy and safe sample loading
- Isolated rear door for easy cleaning maintenance

### Configuration

- Auto Control by 10.5" Touch Panel  
(Auto Pumping, Auto Venting, Auto System Shut Down)
- Co-Sputtering (Optional)
- Sample Heating, Up to 300°C / Cooling, Down to 5°C (Optional)



## Solid-State Battery Deposition / Thermal Evaporation & Sputtering Process



### Characteristics

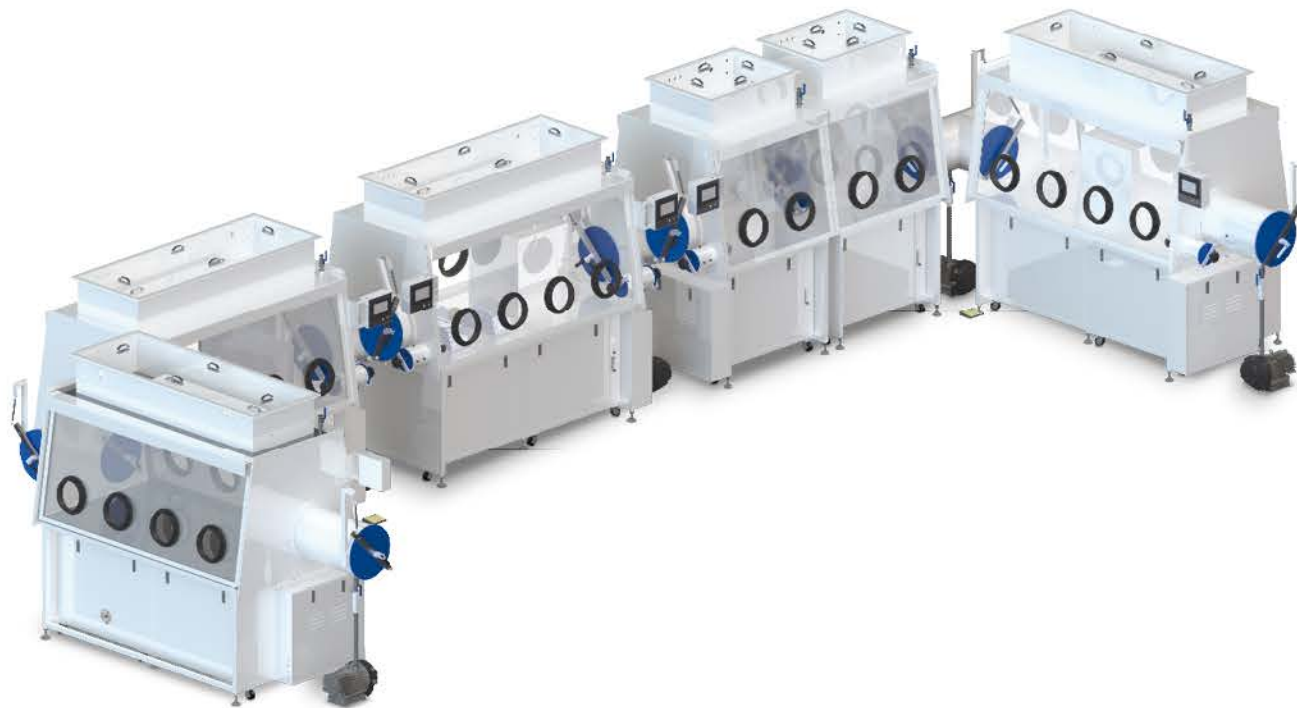
#### Thermal Evaporator Chamber

- Metal source deposition, extra open port for future upgrading
- Sample heating Max. 300°C
- Thickness controller for Co-Deposition
- Dedicated Pumping System
- Bolt free sample loading / unloading

#### Sputter Chamber

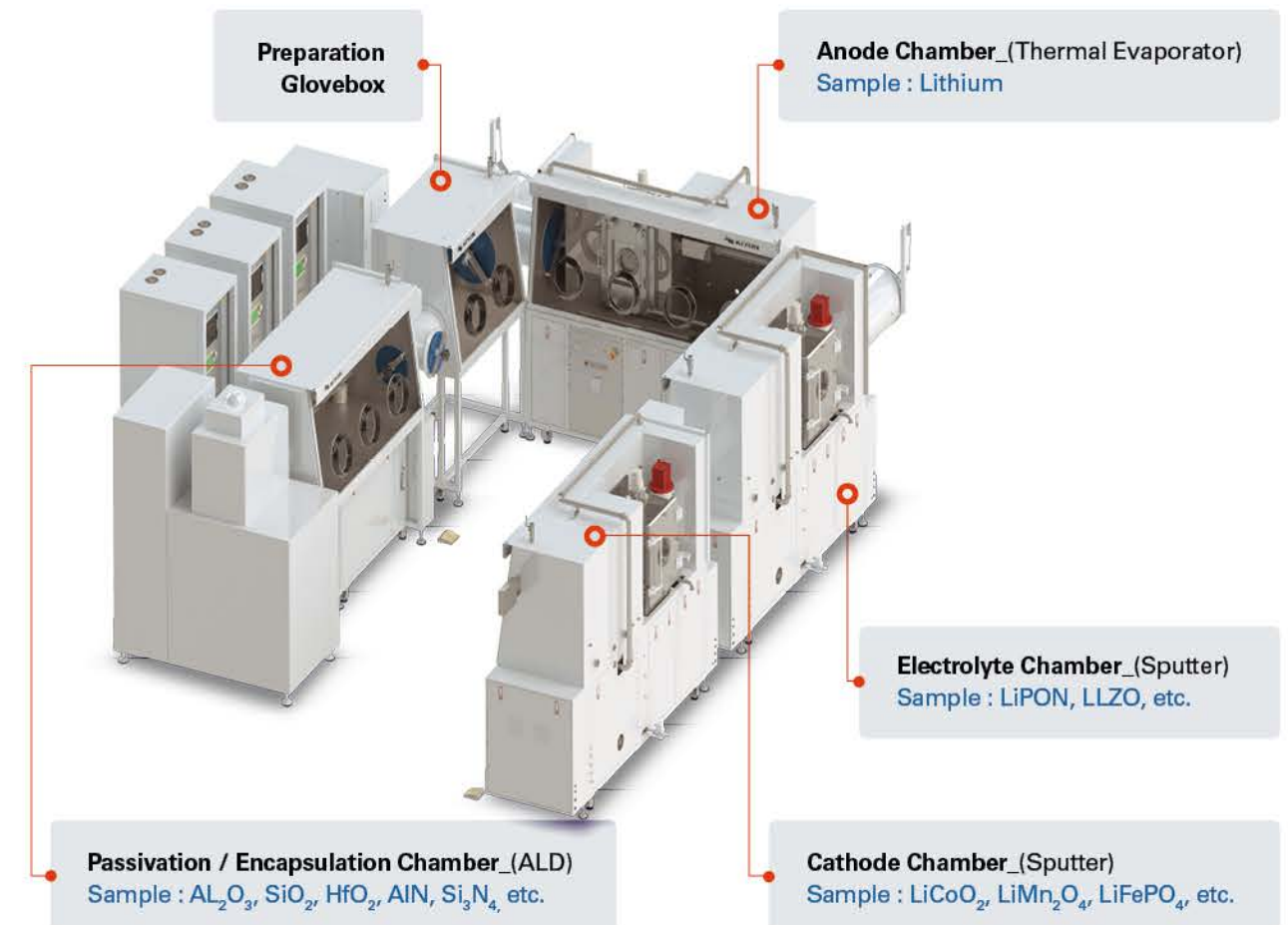
- Sputter Gun 3 sets + 1 Metal Thermal Evaporator
- Sample heating Max. 500°C
- Co-Sputtering
- Dedicated Pumping System
- Special Chamber design to reduce cross-contamination
- Bolt free target loading / unloading

## ASSB (All Solid State Battery) / ASSB Electrode Process



1. <b>Preparation</b>	Material Feeder → Weighing Balance → Sieve Shaker
2. <b>Mixing</b>	Ball Mill → Paste Mixer → Binder Dispenser → Rheology → Grindometer
3. <b>Coating</b>	Mini Coater → Coating Plate, Micrometer Film, Adjustable Applicator, etc.
4. <b>Press</b>	Heating Roll Press → Newton Press → Pellet Mold → KS Solid Cell
5. <b>Punching</b>	Hand Operated Punching Toll for Li Metal, etc.
6. <b>Vacuum Oven</b>	-

## ASSB (All Solid State Battery) / Deposition system to fabricate lithium-based thin-film solid-state batteries



### Separated Vacuum Chambers for Depositing

- Cathode material
- Electrolyte material
- Anode material
- Encapsulation layer

All the deposition chambers integrated with gloveboxes, and interconnected through the gloveboxes, allowing samples to be transferred without exposure to oxygen or humidity.

## Perovskite Solar Cell/ Metal Chamber + Perovskite Chamber



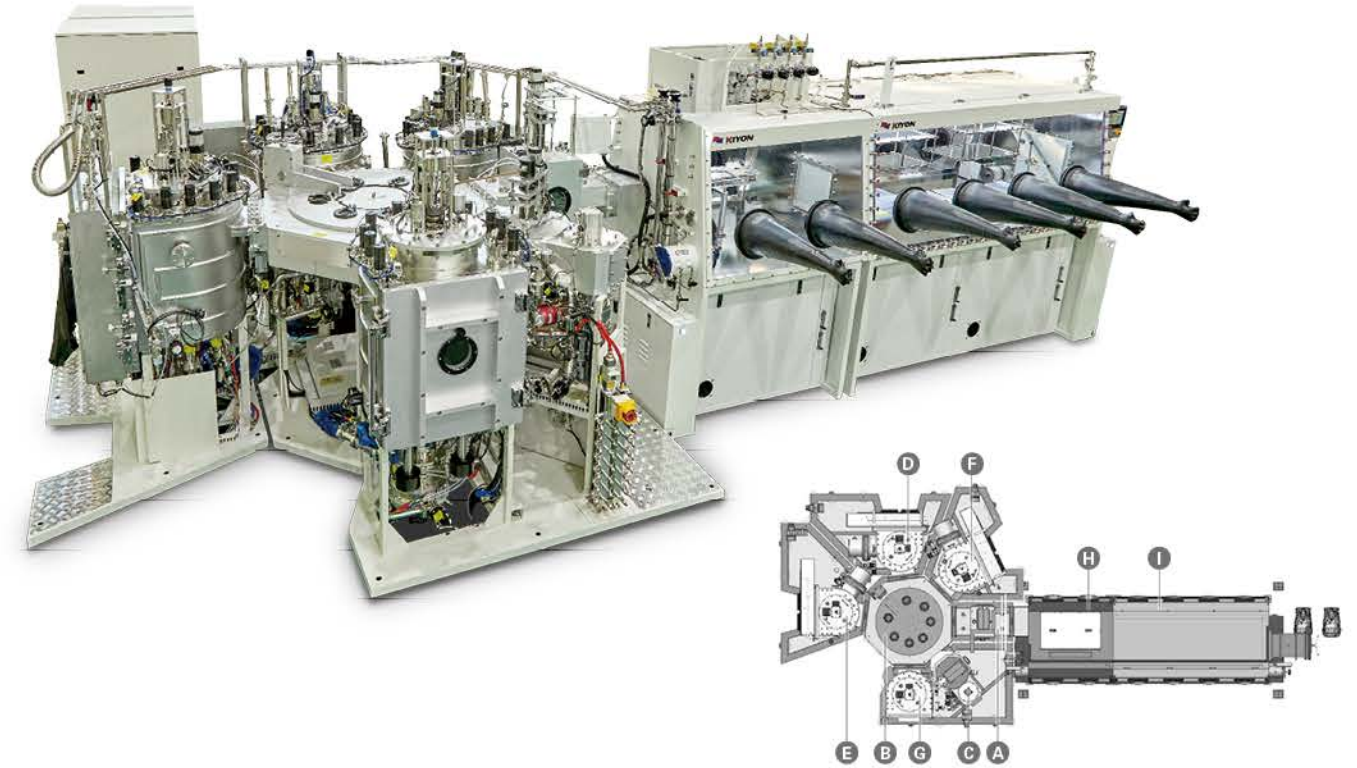
### Characteristics

- Chamber Ultimate Pressure: Below than  $5.0 \times 10^{-7}$  torr within 12 hours
- Chamber Working Pressure: Below than  $5.0 \times 10^{-6}$  torr within 30 Minutes
- Film Thickness Uniformity:  $\pm 5\%$  within 150mm \* 150mm Glass
- 4 Metal + 4 Organic source deposition
- Sample Size: 150mm \* 150mm Glass 1ea

### Configuration

- Front Side Door - Sliding Door Type (Full Open Type)
- Chamber Purging before door opening; interlocking system
- Rear Side Door - Push / Pull Door Type (Full Open Type)
- Rear Side Door - Easy Maintenance & Chamber Cleaning in Glovebox Condition
- Thickness controller Co-Deposition

## Perovskite Solar Cell/ Perovskite / Si Tandem System Cluster System



A. Load lock	D. HTL layer dep. module	G. TCO layer dep. Module
B. Transfer module	E. Perovskite layer dep. module	H. 2-port glove box
C. Plasma treatment module	F. ETL layer dep. module	I. 4-port glove box

- **Sample Size:** Max. 200mm \* 200mm
- **Source Materials:** Perovskite Materials
- **HTL/ETL Chamber:** E-beam
- **PVK :** Thermal Evaporator
- **TCO :** Sputter Technology
- **Wet Process:** Spin coater, Slot Die System inside Glovebox

Glovebox is designed to provide a hermetically sealed & highly customized working space under a very tightly controlled atmosphere.

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Single Type

Double Type

Purification

Customized

Optional Item

## Glovebox KK-011AS



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

Number of Users	Glove Ports	Oxygen & Moisture
 <b>1</b> Person	 <b>2</b> EA	 Less than <b>1</b> PPM

### Specifications

Basic Composition	Dimension	1,200 (L) x 900 (H) x 780 (D) mm
	Material	SUS304
	Windows	Poly-Carbonate PC or Safety Glass
	Glove	Butyl Rubber 1 Pair
	External Light	1 ea (LED)
	Service Port	KF (NW40): 2 ea
	Leak Test	0.05 vol%/hr in accordance with ISO 10648-2
Antechamber	Size	390 x 600 mm
	Vacuum Capacity	1 x 10 <sup>-3</sup> torr
	Tray	220 x 580 mm
Mini-Antechamber	Size	150 x 290 mm
Purifier System	Purity Level	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Catalyst	Oxygen Catalyst and Molecular Sieve
	PLC	Automatic PLC Control
	Control Panel	7" Full Color Touch Screen
	Purifier Regeneration	Auto Regeneration Programmed on PLC
	Blower Speed Control	Max. 63 CFM (1.78 m <sup>3</sup> /min)
	Vacuum Pump	180 ℓ/min
Stand	Dimension	1,200 (L) x 936 (H) x 780 (D) mm

## Glovebox KK-011AS EXTRA



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

Number of Users	Glove Ports	Oxygen & Moisture
 <b>1.5</b> Person	 <b>3</b> EA	 Less than <b>1</b> PPM

### Specifications

Basic Composition	Dimension	1,800 (L) x 900 (H) x 780 (D) mm
	Material	SUS304
	Windows	Poly-Carbonate PC or Safety Glass
	Glove	Butyl Rubber 1.5 Pair
	External Light	1 ea (LED)
	Service Port	KF (NW40): 2 ea
	Leak Test	0.05 vol%/hr in accordance with ISO 10648-2
Antechamber	Size	390 x 600 mm
	Vacuum Capacity	1 x 10 <sup>-3</sup> torr
	Tray	220 x 580 mm
Mini-Antechamber	Size	150 x 290 mm
Purifier System	Purity Level	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Catalyst	Oxygen Catalyst and Molecular Sieve
	PLC	Automatic PLC Control
	Control Panel	7" Full Color Touch Screen
	Purifier Regeneration	Auto Regeneration Programmed on PLC
	Blower Speed Control	Max. 63 CFM (1.78 m <sup>3</sup> /min)
	Vacuum Pump	180 ℓ/min
Stand	Dimension	1,800 (L) x 936 (H) x 780 (D) mm

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Single Type

Double Type

Purification

Customized

Optional Item

## Glovebox KK-021AS



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

Number of Users	Glove Ports	Oxygen & Moisture
 <b>2</b> Person	 <b>4</b> EA	 Less than <b>1</b> PPM

### Specifications

Basic Composition	Dimension	2,200 (L) x 900 (H) x 780 (D) mm
	Material	SUS304
	Windows	Poly-Carbonate PC or Safety Glass
	Glove	Butyl Rubber 2 Pair
	External Light	1 ea (LED)
	Service Port	KF (NW40): 2 ea
	Leak Test	0.05 vol%/hr in accordance with ISO 10648-2
Antechamber	Size	390 x 600 mm
	Vacuum Capacity	1 x 10 <sup>-3</sup> torr
Mini-Antechamber	Tray	220 x 580 mm
Purifier System	Size	150 x 290 mm
	Purity Level	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Catalyst	Oxygen Catalyst and Molecular Sieve
	PLC	Automatic PLC Control
	Control Panel	7" Full Color Touch Screen
	Purifier Regeneration	Auto Regeneration Programmed on PLC
	Blower Speed Control	Max. 63 CFM (1.78 m <sup>3</sup> /min)
Stand	Vacuum Pump	180 ℓ/min
	Dimension	2,200 (L) x 936 (H) x 780 (D) mm

## Glovebox KK-011AD



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

Number of Users	Glove Ports	Oxygen & Moisture
 <b>2</b> Person	 <b>4</b> EA	 Less than <b>1</b> PPM

### Specifications

Basic Composition	Dimension	1,200 (L) x 900 (H) x 1200 (D) mm
	Material	SUS304
	Windows	Poly-Carbonate PC or Safety Glass
	Glove	Butyl Rubber 2 Pair
	External Light	2 ea (LED)
	Service Port	KF (NW40): 2 ea
	Leak Test	0.05 vol%/hr in accordance with ISO 10648-2
Antechamber	Size	390 x 600 mm
	Vacuum Capacity	1 x 10 <sup>-3</sup> torr
Mini-Antechamber	Material	SUS 304
Purifier System	Size	150 x 290 mm
	Purity Level	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Catalyst	Oxygen Catalyst and Molecular Sieve
	PLC	Automatic PLC Control
	Control Panel	7" Full Color Touch Screen
	Purifier Regeneration	Auto Regeneration Programmed on PLC
	Blower Speed Control	Max. 63 CFM (1.78 m <sup>3</sup> /min)
Stand	Vacuum Pump	180 ℓ/min
	Dimension	1,200 (L) x 936 (H) x 1,200 (D) mm

Glovebox is designed to provide a hermetically sealed & highly customized working space under a very tightly controlled atmosphere.

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Single Type Double Type Purification Customized Optional Item

## Glovebox KK-021AD



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

Number of Users	Glove Ports	Oxygen & Moisture
 4 Person	 8 EA	 Less than 1 PPM

### Specifications

Basic Composition	Dimension	2,200 (L) x 900 (H) x 1,200 (D) mm
	Material	SUS304
	Windows	Poly-Carbonate PC or Safety Glass
	Glove	Butyl Rubber 4 Pair
	External Light	4 ea (LED)
	Service Port	KF(NW40): 2 ea
	Leak Test	0.05 vol%/hr in accordance with ISO 10648-2
Antechamber	Size	390 x 600 mm
	Vacuum Capacity	1 x 10 <sup>-3</sup> torr
Mini-Antechamber	Material	SUS 304
Purifier System	Size	150 x 290 mm
	Purity Level	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Catalyst	Oxygen Catalyst and Molecular Sieve
	PLC	Automatic PLC Control
	Control Panel	7" Full Color Touch Screen
	Purifier Regeneration	Auto Regeneration Programmed on PLC
	Blower Speed Control	Max. 63 CFM (1.78 m <sup>3</sup> /min)
Stand	Vacuum Pump	180 ℓ/min
	Dimension	2,200 (L) x 936(H) x 1,200 (D) mm

## Glovebox KK-PURI



### Optional Accessories

- N2 Safety Interlock & N2 Hazard System
- Oxygen & Moisture sensor
- Solvent Trap
- Vacuum Oven
- Freezer
- Feedthroughs
- Others

### Specifications

Purifier System	Automatic Atmosphere Reduction Control	Less than 1 ppm O <sub>2</sub> and H <sub>2</sub> O
	Oxygen/Moisture Removal to less than 1 ppm, Control	PLC type (Heat, Vacuum, Purge, Refill: 13 hours)
	Circulation Blower Capacity	63 CFM (Variable Speed Control)
	Controller	Automatic Pressure Controller (7" Full Color Touch Panel)
	Pressure Range	-12.5 to 12.5 mbar, Limits easily adjustable
	Manual Foot Switch	Operable
	Circulation port	NW 40
	Vacuum Pump	180 ℓ/min.
	Catalyst	Oxygen Catalyst and Molecular Sieve
	Power	220 V
Phase	1 Phase	

Glovebox is designed to provide a hermetically sealed & highly customized working space under a very tightly controlled atmosphere.

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Single Type

Double Type

Purification

Customized

Optional Item

## Glovebox Customization



Vibration-free Glovebox for SEM, AFM, Photolithography



Microscope



Quick Clamp



Laminar flow + Evaporator



Elevator chamber + hoist



Anti-Explosion



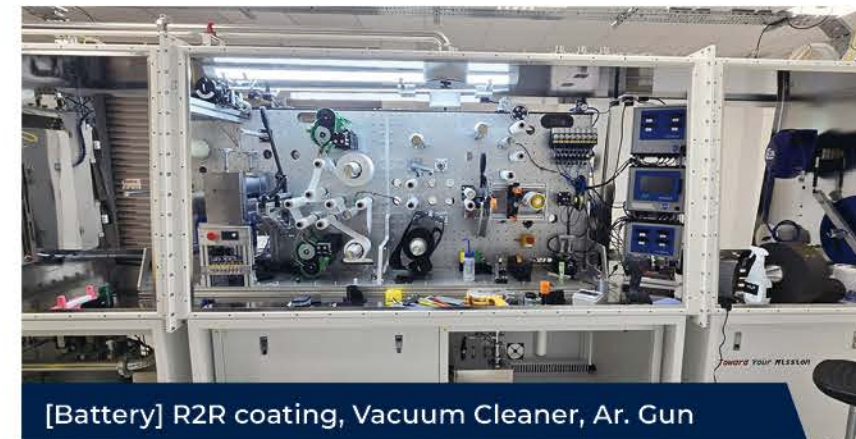
Stand-alone Purification System



Electric Furnace Integration



Freezer



[Battery] R2R coating, Vacuum Cleaner, Ar. Gun



UV Coating



Slot Die integration



Multi-Ports



Teflon Coating

Glovebox is designed to provide a hermetically sealed & highly customized working space under a very tightly controlled atmosphere.

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Single Type

Double Type

Purification

Customized

Optional Item

## Glovebox Optional Item



Moisture Analyzer

### Specifications

- Thin-film aluminum oxide type
- Microprocessor based, all digital technology for reliable operation
- Compact size
- Loop powered 4 to 20 mA output
- NIST traceable calibration
- Accuracy : +/- 2 °C
- Measurement range : 0 ~ 1,000 ppm
- Output : 4-20 mA DC Active
- Sensor :Thin-film capacitive polymer sensor



Oxygen Analyzer

### Specifications

- Measurement system: Zirconia Oxygen concentration cell
- Measurement range: 0.1 ppm – 100%
- Display range: 0-1,000 ppm
- Compliant standard: CE marking and RoHS
- Microprocessor based, all digital technology for reliable operation
- Loop powered 4 to 20 mA output



N2 Analyzer

### Specifications

Analyzer to selectively measure trace N2 in Ar/He gas, that influence materials oxidation such as Lithium, etc



Gas Hazard

### Specifications

Gas hazard system is for system mechanical safety, monitors Glovebox inside pressure, and automatically shutting down working gas inlet.



Refrigerator

### Specifications

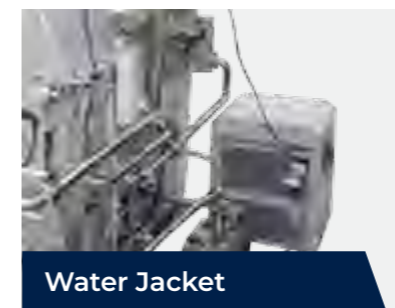
- Stainless steel shelves be fitted on left side
- Temperature Range: Room temp. to -35°C
- Refrigerant: 404A
- Working Size: 220 (L) x 515 (H) x 170 (D) mm



Vacuum Oven

### Specifications

- Inner diameter: 300 mm
- This device can be installed inside an existing Antechamber in accordance with customer's requirement.
- It can also be installed alone in the other direction of the glovebox.
- Single wall S/S cylinder, internally inconel mounted.
- Working Size : 180 (W) x 200 (H) x 600 (L) mm
- Operational Temperature: up to 200°C
- Using Temp. : 150°C



Water Jacket



Gas Interlock / Safety



Solvent Trap



Door Cooling



APC



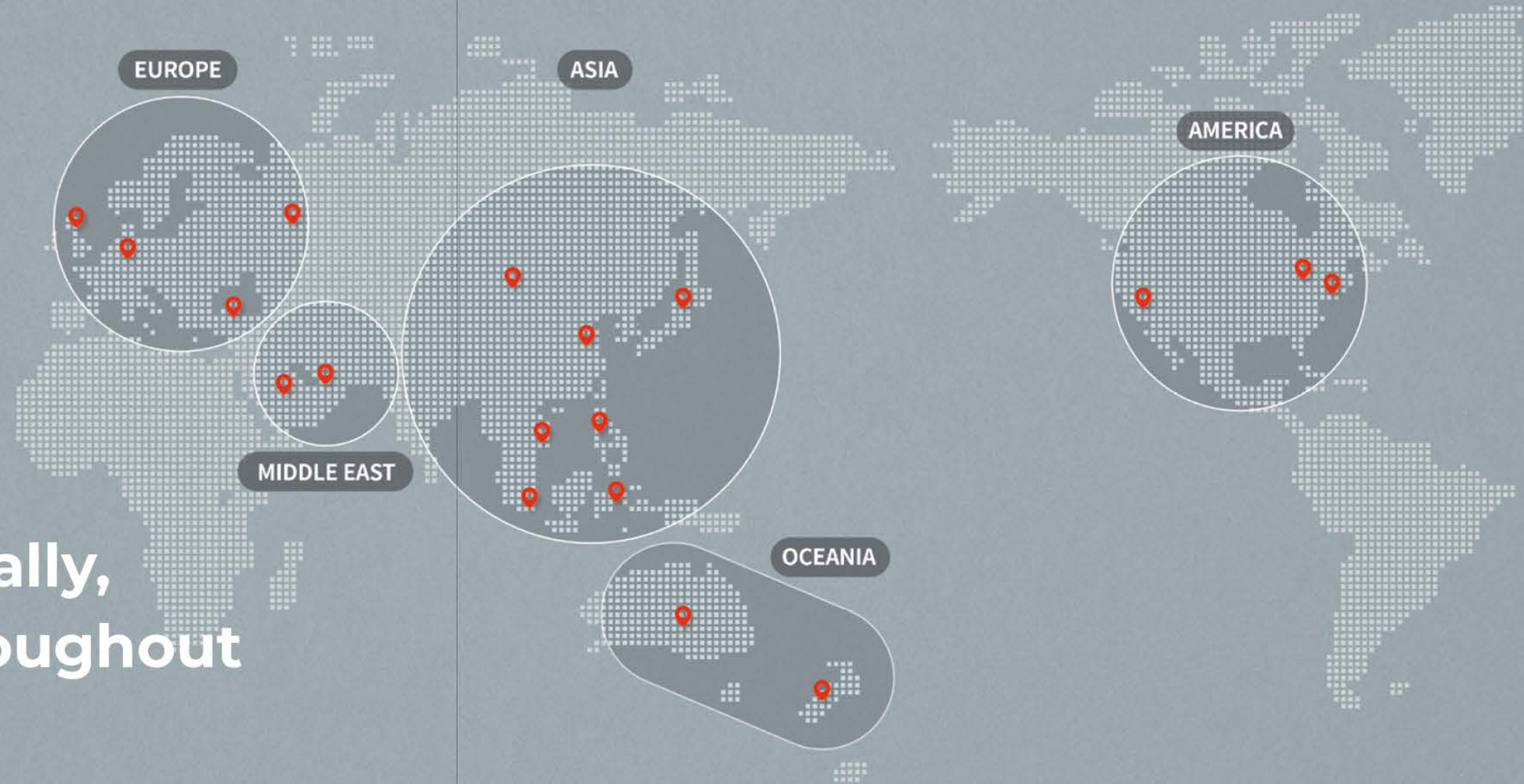
Auto Box Purging



NW40, PCB Feedthru

# Global Presence

**KOREA KIYON,  
recognized globally,  
is spreading throughout  
the world!!**



EUROPE	 U.K.	 NETHERLAND
	 RUSSIA	 TURKEY
MIDDLE EAST	 UAE	 SAUDI
OCEANIA	 AUSTRALIA	 NEW ZEALAND

ASIA	 INDIA	 JAPAN
	 TAIWAN	 THAILAND
	 VIETNAM	 SINGAPORE
	 CHINA	
America	 CANADA	 USA



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